



Customer No. 22,852  
Attorney Docket No.: 03327.2306

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:	)	
	)	
<b>Shuichi MAENO</b>	)	
	)	Group Art Unit: <b>2858</b>
Application No.: <b>10/665,262</b>	)	
	)	Examiner: <b>Not Yet Assigned</b>
Filed: <b>September 22, 2003</b>	)	
	)	
For: <b>CHARGING VOLTAGE</b>	)	
<b>MEASURING DEVICE FOR SUBSTRATE</b>	)	
<b>AND ION BEAM IRRADIATING DEVICE</b>	)	

**Initial Patent Examination Division  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450**

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicant brings to the Examiner's attention the documents listed on attached Form PTO-1449. Copies of the listed documents are attached. Applicant respectfully requests that the Examiner consider the documents listed on attached Form PTO-1449 and indicate that they were considered by making an appropriate notation on this form. This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits for the above-referenced application.

The following are listed on the accompanying PTO-1449 and are in a non-English language:

1. Japanese Patent Publication No. 10-027566. In a process or apparatus having a fear that the surface of the substrate is electrified, it is important to measure a

charging voltage on a substrate surface to prevent dielectric breakdown on the substrate surface. This document discloses a specific apparatus employing an electrostatic chuck on the substrate holding unit for holding the substrate, a technique for acquiring a potential on the substrate surface from an adsorption current flowing through the electrodes of the electrostatic chuck (paragraph number 0010 to 0015, Fig. 1), though this technique is not applicable when the electrostatic chuck is not employed.

2. Japanese Patent Publication No. 09-054130 . In a process or apparatus having a fear that the surface of the substrate is electrified, it is important to measure a charging voltage on a substrate surface to prevent dielectric breakdown on the substrate surface. This document discloses a specific apparatus employing an electrostatic chuck on the substrate holding unit for holding the substrate, a technique for acquiring a potential on the substrate surface from an adsorption current flowing through the electrodes of the electrostatic chuck (paragraph number 0010 to 0014, Fig. 1), though this technique is not applicable when the electrostatic chuck is not employed.

An English language abstract of the listed documents above is also enclosed.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicant determines that the cited documents do not constitute "prior art" under United States law, applicant reserves the right to present to the Office the relevant facts and law regarding the appropriate status of such documents. Applicant further reserves the right to take appropriate action to establish the patentability of


the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

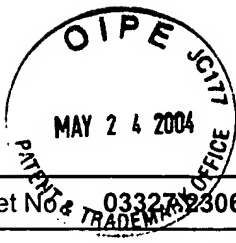
Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: May 24, 2004

By:   
Ernest F. Chapman  
Reg. No. 25,961

Enclosures  
EFC/FPD/sci



## INFORMATION DISCLOSURE CITATION

OMB No. 0651-0011

Atty. Docket No. 033275306	Application No. 10/665,262
Applicant <b>Shuichi MAENO</b>	
Filing Date <b>September 22, 2003</b>	Group: <b>2858</b>

## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

## FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
10-027566	01/27/98	JAPAN			ABSTRACT
09-054130	02/25/97	JAPAN			ABSTRACT

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


Examiner	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce